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NOV -5 2001 PATENT APPLICATION

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TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
TADAHIRO OHMI, ET AL.) Examiner: D. Monbleau
Application No.: 09/425,015) Group Art Unit: 2881
Filed: October 25, 1999)
For: GAS SUPPLY PATH)
STRUCTURE, GAS SUPPLY :
METHOD, LASER OSCILLATING)
APPARATUS, EXPOSURE :
APPARATUS, AND DEVICE)
PRODUCTION METHOD : October 31, 2001

Commissioner for Patents
Washington, D.C. 20231

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

This paper is filed in response to the Restriction Requirement dated September 7, 2001, requiring Applicants to elect one of the following groups of claims:

Group I: Group I (Claims 1-40), directed to a laser oscillating apparatus;

and

Group II: Group II (Claims 41-44), directed to an exposure apparatus.